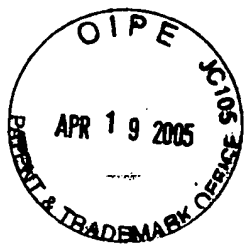


JC10 Rec'd PTO 19 APR 2005



**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on April 15, 2005.

David H. Brinkman, Reg. No. 40,532

Date

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Martin Hausner  
Serial No.: 10/524,525  
Filed: February 11, 2005  
Confirmation No.: 1134  
Group Art Unit: Unknown  
Examiner: Unknown  
Title: **METHOD FOR SELECTIVELY REMOVING MATERIAL FROM THE SURFACE OF A SUBSTRATE, MASKING MATERIAL FOR A WAFER, AND WAFER WITH MASKING MATERIAL**  
Our Ref.: BEET-09

Cincinnati, Ohio 45202

April 15, 2005

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

In accordance with the duty of candor and good faith imposed by 37 C.F.R. §1.56 and means of complying therewith according to 37 C.F.R. §§1.97 and 1.98, the references listed on the attached Form PTO-1449 are called to the attention of the United States Patent and Trademark Office in connection with the

above-identified patent application. A copy of the English Translation of the International Preliminary Examination Report is enclosed herewith along with copies of KR2002041363A (D1) and Characterization of a Time Multiplexed Inductively Coupled Plasma Etcher article by Ayon et al. (D2) cited in the International Preliminary Examination Report. The references D3 and D4 cited in the International Preliminary Examination Report were previously made of record in Applicants' Information Disclosure Statement mailed on February 11, 2005.

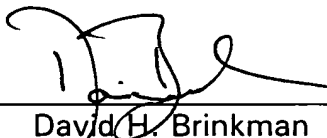
No representation is made that the cited art is the only art or that the cited art represents the best art.

The Examiner is urged to consider the cited document and to make an independent evaluation of the teachings and materiality of it.

No fees are believed to be due. However, if any additional fees are necessary to complete this communication, please apply them to Deposit Account No. 23-3000.

Respectfully submitted,

WOOD, HERRON & EVANS, L.L.P.

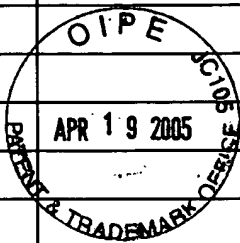
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SUBSTITUTE FORM PTO-1449 (MODIFIED)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. BEET/09	SERIAL NO. 10/524,525
INFORMATION DISCLOSURE STATEMENT BY APPLICANT  (Use several sheets if necessary)  (37 CFR 1.98(b))				APPLICANT Martin Hausner	
				FILING DATE February 11, 2005	CONFIRMATION NO. 1134

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A.A						
	A.B						
	A.C						
	A.D						
	A.E						
	A.F						
	A.G						
	A.H						
	A.I						
	A.J						
	A.K						



## FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

		DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION (YES/NO)
	A.L	KR 2002041363A	06/2002	Republic of Korea	H01L	21/3065	No
	A.M						
	A.N						
	A.O						
	A.P						
	A.Q						

## OTHER DOCUMENTS (Including Author, Title, Date, Place of Publication)

A.R	Ayon et al., <u>Characterization of a Time Multiplexed Inductively Coupled Plasma Etcher</u> , Journal of the Electrochemical Society, January 1999, Vol. 146, Issue 1, pp. 339-349
A.S	The International Bureau of WIPO, <u>English Translation of the International Preliminary Examination Report</u> , November 17, 2004 (12 pages)
A.T	

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not in conformance. Draw line through citation only if not in conformance and not considered. Include a copy of this form with next communication to applicant.